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Total Number of Pages in This Submission

Application Number	TBD
Filing Date	November 12, 2003
First Named Inventor	CHOU et al.
Art Unit	TBD
Examiner Name	TBD
Attorney Docket Number	14002-7

### ENCLOSURES (check all that apply)

<input type="checkbox"/> Fee Transmittal Form	<input type="checkbox"/> Drawing(s)	<input type="checkbox"/> After Allowance communication to Group
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### SIGNATURE OF APPLICANT, ATTORNEY, OR AGENT

Firm or Individual name	GLEN E. BOOKS (REG. NO. 24,950) LOWENSTEIN SANDLER PC 65 LIVINGSTON AVENUE, ROSELAND, NJ 07068	
Signature		
Date	3/16/04	

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14002-7



PATENT APPLICATION

THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of: )  
Chou et al. ) : Examiner: TBA  
Application No.: TBA ) : Group Art Unit: TBA  
Filed: November 12, 2003 ) :  
For: COMPOSITIONS AND PROCESSES )  
FOR NANOIMPRINTING ) : March 16, 2004

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

INFORMATION DISCLOSURE STATEMENT

Sir:

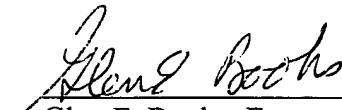
In compliance with the duty of disclosure under 37 C.F.R. § 1.56 and in accordance with the practice under 37 C.F.R. §§ 1.97 and 1.98, the Examiner's attention is directed to the documents listed on the enclosed PTO-1449. Copies of the listed documents are also enclosed. It is respectfully requested that the PTO-1449 form be initialed and returned, indicating that the cited reference has been considered.

CONCLUSION

Applicants' undersigned attorney may be reached by telephone at (973) 597-2500.

All correspondence should continue to be directed to our address listed below.

Respectfully submitted,

  
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**INFORMATION DISCLOSURE CITATION**  
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MAR 16 2004

ATTY DOCKET NO.  
14002-7

SERIAL NO.

TBD

Chou et al.

FILING

November 12, 2003

GROUP

TBD

**U.S. PATENT DOCUMENTS**

*EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
	4,592,081	05/27/1986	Eaton et al.			
	4,211,489	07/08/1980	Kleinknecht et al.			
	2,302,024	11/17/1942	Goss, Jr.			
	3,742,229	06/26/1973	Smith et al.			
	3,951,548	04/20/1976	Westell			
	4,037,325	07/26/1977	Weber et al.			
	4,200,395	04/29/1980	Smith et al.			
	4,475,223	10/02/1984	Taniguchi et al			
	4,588,468	05/13/1986	McGinty et al.			
	4,883,563	11/28/1989	Kotani et al.			
	6,056,526	05/02/00	Sato			

**FOREIGN PATENT DOCUMENTS**

		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
							YES	NO
		1196749	01/30/1988	Japan w/English Abstract				
		244884	03/28/1986	European				
		4255307	09/10/1992	Japan w/English Abstract				
		4332694	08/05/1991	Japan w/English Abstract				

**OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)**

		Broers, et al., "250-A Linewidths with PMMA Electron Resist", <u>Applied Physics Letter 33 (5)</u> , 1978 American Institute of Physics, 392-394, (September 1, 1978)
		Chou, S.Y., et al., "Imprint Lithography with 25-Nanometer Resolution", <u>Science, Vol. 272</u> , 85-87, (April 5, 1996)

EXAMINER	DATE CONSIDERED
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\*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

**INFORMATION DISCLOSURE CITATION**  
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ATTY DOCKET NO. 14002-15	SERIAL NO. TBD
<b>Chou et al.</b>	
FILING November 12, 2003	GROUP TBD

**U.S. PATENT DOCUMENTS**

*EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
		5,352,394	10/04/1994	Fujita et al.			
		3,743,842	07/03/1973	Smith, H.I., et al.			
		4,310,743	01/12/1982	Seliger, R.L.			
		4,383,026	05/10/1983	Hall, T.M.			
		4,450,358	05/22/1984	Reynolds, G.O.			
		4,498,009	02/05/1985	Reynolds, G.O.			
		4,516,253	05/07/1985	Novak, W.T.			
		4,552,615	11/12/1985	Amendola, A., et al.			
		4,576,678	03/18/1986	Shibata, H.			
		4,606,788	08/19/1986	Moran, P.L.			
		4,731,155	03/15/1988	Napoli, L.S., et al.			

**FOREIGN PATENT DOCUMENTS**

		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
							YES	NO
		9117565	11/14/1991	PCT				
		98/26913	06/25/1998	PCT				
		WO 93/21671	10/28/1993	PCT				

**OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)**

		Early, K., et al., "Absence of Resolution Degradation in X-Ray Lithography for Wavelength from 4.5nm to 0.83nm", <u>Microelectronic Engineering 11</u> , Elsevier Science Publishers B.V., 317-321, (1990)
		Fischer, et al., "10 nm Electron Beam Lithography and sub-50 nm Overlay Using a Modified Scanning Electron Microscope", <u>Applied Physics Letter 62 (23)</u> , 1993 American Institute of Physics, 2989-2991 (June 7, 1993)

EXAMINER	DATE CONSIDERED
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<b>INFORMATION DISCLOSURE CITATION</b> <i>(Use several sheets if necessary)</i>			ATTY DOCKET NO. <b>14002-15</b>		SERIAL NO. <b>TBD</b>			
			Chou et al.					
			FILING <b>December 10, 2003</b>	GROUP		<b>TBD</b>		
<b>U.S. PATENT DOCUMENTS</b>								
*EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE	
		3,833,303	09/03/1974	Burns et al.				
		4,325,779	04/20/1982	Rossetti, J.J.				
		4,832,790	05/23/1989	Rossetti, J.J.				
		5,277,749	01/11/1994	Griffith, J.H., et al.				
		5,861,113	01/19/1999	Choquette, S.J., et al.				
		5,032,216	07/16/1991	Felten				
		5,152,861	10/06/1992	Hann				
		4,664,862	05/12/1987	Ghavamikia				
		5,253,409	10/19/1993	Bier et al.				
		5,234,571	08/10/1993	Noeker				
	~	4,738,010	04/19/1988	Ehrfeld et al.				
<b>FOREIGN PATENT DOCUMENTS</b>								
		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
							YES	NO
<b>OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)</b>								
		Hara, et al., "An Alignment Technique Using Diffracted Moire Signals", <u>J. Vac. Sci. Technol. B7 (6)</u> , 1989 American Vacuum Society, 1977-1979, (Nov./Dec. 1989)						
		Harmening, et al., "Molding of Threedimensional Microstructures by the Liga Process" <u>Proceedings IEEE: Micro Electro Mechanical Systems</u> , Travemunde, Germany, 202-207, (1992)						
EXAMINER				DATE CONSIDERED				
<small>*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.</small>								

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(Use several sheets if necessary)

ATTY DOCKET NO. 14002-7	SERIAL NO. TBD
Chou et al.	
FILING November 12, 2003	GROUP TBD

**U.S. PATENT DOCUMENTS**

*EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
		5,119,151	06/02/1992	Onda			
		4,781,790	11/01/1988	Wu			
		4,788,015	11/29/1988	Sakai et al.			
		4,294,650	10/13/1981	Werthmann			
		3,923,566	12/02/1975	Law			
		5,259,926	11/09/1993	Kuwabara et al.			
		5,425,848	06/20/1995	Haisma et al.			
		5,503,963	04/02/1996	Bifano			
		4,543,225	09/24/1985	Beaujean			
		5,434,107	07/18/1995	Paranjpe			
		5,338,396	08/16/1994	Abdala et al.			

**FOREIGN PATENT DOCUMENTS**

		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
							YES	NO

**OTHER DOCUMENTS** (Including Author, Title, Date, Pertinent Pages, Etc.)

		Li, et al., "Molding of Plastic Components Using Micro-EDM Tools", <u>IEEE/CHMT International Electronics Manufacturing Technology Symposium 145-149, (1992)</u>
		Nomura, et al., "Moire Alignment Technique for the Mix and Match Lithographic System: <u>J. Vacuum Society Technol. B6 (1), American Vacuum Society, 394-398, (Jan/Feb 1988)</u>

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				Chou et al.			
				FILING November 12, 2003	GROUP	TBD	
U.S. PATENT DOCUMENTS							
*EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
		5,471,455	05/17/1994	Jabr			
		4,287,235	05/29/1979	Flanders			
		4,512,848	04/23/1985	Deckman et al.			
		5,638,355	06/10/1997	Jabr			
		5,259,926	11/09/1993	Kuwabara et al. (Duplicate)			
FOREIGN PATENT DOCUMENTS							
		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION
							YES
OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)							
		Kamins, T.I., et al., "Positioning of Self-Assembled, single-crystal,germanium islands by silicon nanoimprinting" Applied Physics Letter, Vol. 74, No. 12, March 22, 1999.					
		Wang, J., et al., "Fabrication of a new broadband waveguide polarizer with a double-layer 190 nm period metal-gratings using nanoimprint lithography" J. Vac. Sc. Technol. B 17 (6) Nov/Dec 1999.					
EXAMINER				DATE CONSIDERED			



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